Date of Deposit: June 28, 2004

Infineon Ref. No. P26985 Our Case No. 10808/109

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

fire Application of:)
E. Steinkirchner et al.)
Serial No. 10/712,418) Examiner: Unknown
Filing Date: November 12, 2003) Group Art Unit No. Unknown
For METHOD, PREPARATIONS, COMPUTER LEGIBLE AGENT AND COMPUTER PROGRAM ELEMENT FOR THE CALCULATED SUPPORT CONTROL OF PROCESS PARAMETERS FOR PHYSICAL OBJECTS)))))))))

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents Alexandria, VA 22313-1450

Dear Sir:

In compliance with the duty of disclosure under 37 C.F.R. § 1.56, it is respectfully requested that this Information Disclosure Statement be entered and the documents listed below and on the attached Form PTO-1449 be considered by the Examiner and made of record. Copies of the listed documents required by 37 C.F.R. § 1.98(a)(2) are enclosed for the convenience of the Examiner.

The references now cited are the following:

U.S. PATENTS

Document No.	<u>Date</u>	Inventor
5,586,041	12/17/1996	Mangrulkar
5,726,920	03/10/1998	Chen et al.
2002/0055194 A1	05/09/2002	Takanabe

FOREIGN PATENT DOCUMENTS

Document No.	<u>Date</u>	Country
GB 2 283 116 A	04/26/1995	United Kingdom

OTHER ART

Copy of European Search Report dated March 10, 2004 for European Patent Application No. 03026035

C. Schneider et al., "Automated Photolithography Critical Dimension Controls In A Complex, Mixed Technology, Manufacturing Fab", IBM Microelectronics, 2001 IEEE/SEMI Advanced Semiconductor Manufacturing Conference

In accordance with 37 C.F.R. § 1.97(g),(h), this Information Disclosure Statement is not to be construed as a representation that a search has been made and is not to be construed to be an admission that the information cited is, or is considered to be, material to patentability as defined in 37 C.F.R. § 1.56(b).

This Information Disclosure Statement is being filed prior to the receipt of the first Official Action reflecting an examination on the merits and hence is believed to be timely filed in accordance with 37 C.F.R. § 1.97(b). No fees are believed to be due in connection with filing of this Information Disclosure Statement, however, should any fees under 37 C.F.R. §§ 1.16 to 1.21 be deemed necessary for any reason relating to these material, the Commissioner is hereby authorized to deduct said fees from Brinks Hofer Gilson & Lione Deposit Account No. 23-1925. A duplicate copy of this document is enclosed.

Applicant(s) respectfully request that the listed documents be made of record in the present case.

Respectfully submitted,

oh J. King

Registration No. 35,918 Attorney for Applicant(s)

BRINKS HOFER GILSON & LIONE P.O. Box 10395 Chicago, IL 60610 (312) 321-4200

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FORM PTO-1449	JUN Z & LOO	SERIAL NO.	CASE NO.
	P. S.	10/712,418	10808/109
LIST OF PATENTS AND PUBLICA APPLICANT'S INFORMATION DIS	TIONS FOR	FILING DATE	GROUP ART UNIT
APPLICANT'S INFORMATION DIS	SCLOSURE	November 12, 2003	Unknown
STATEMENT			
(use several sheets if necessary)	•	APPLICANT(S): E. Steinkirchne	r et al.

REFERENCE DESIGNATION

U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER Number-Kind Code (if known)	DATE	NAME	CLASS/ SUBCLASS	FILING DATE
	A1	5,586,041	12/17/1996	Mangrulkar		_
	A2	5,726,920	03/10/1998	Chen et al.		
	A3	2002/0055194 A1	05/09/2002	Takanabe		

FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER Number-Kind Code (if known)	DATE	COUNTRY	CLASS/ SUBCLASS	TRANSLATION YES OR NO
	A4	GB 2 283 116 A	04/26/1995	United Kingdom		

EXAMINER INITIAL		OTHER ART — NON PATENT LITERATURE DOCUMENTS Include name of author, title of the article (when appropriate), title of the item (book, magazine, journal, serial, apposium, catalog, etc.), date page(s), volume-issue number(s), publisher, city and/or country where published.
	A5	Copy of European Search Report dated March 10, 2004 for European Patent Application No. 03026035
	A6	C. Schneider et al., "Automated Photolithography Critical Dimension Controls In A Complex, Mixed Technology, Manufacturing Fab", IBM Microelectronics, 2001 IEEE/SEMI Advanced Semiconductor Manufacturing Conference

EVAMINED	DATE CONSIDERED
EXAMINER	J DATE CONSIDERED
 	

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Rev. Dec.-99 Document2